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**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No.: 10/088,306

Group Art Unit: 1754

Confirmation No.: 2926

Examiner: Paul A. Wartalowicz

Filed: March 18, 2002

For: **CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT**

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one (1) month, extending the time for responding to the Office Action of November 16, 2005 to March 16, 2006.

A check for the statutory fee of \$120.00 is attached. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

03/17/2006 HALI11 00000029 10088306

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120.00 DP

Respectfully submitted,

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WASHINGTON OFFICE

**23373**

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Date: March 16, 2006